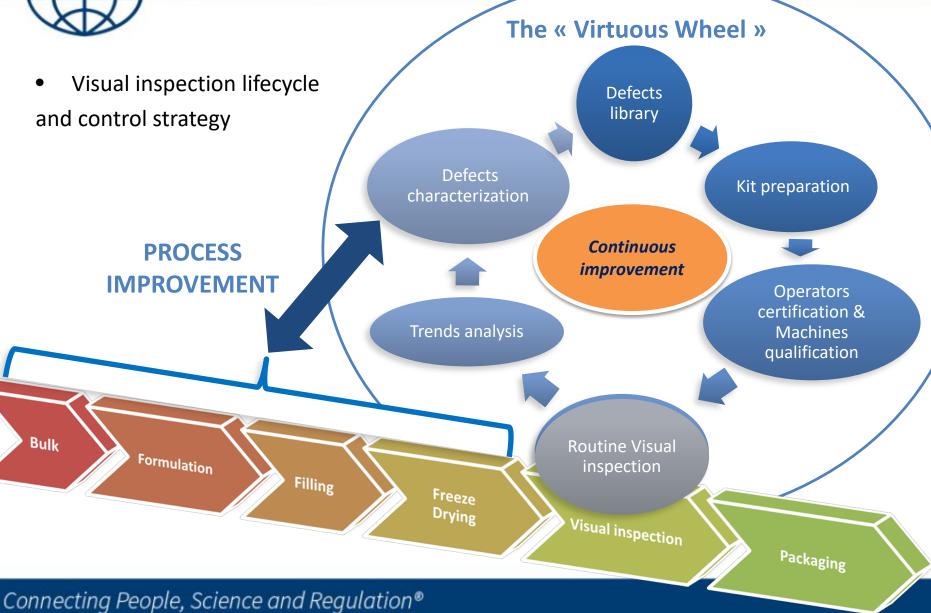


Theory 7



- Integration of visual inspection into overall manufacturing process
- Elements of lifecycle
- Particle identification/characterization
- Defect libraries as dynamic database
- AQL and control charting







Theory 7: Visual inspection lifecycle and control strategy

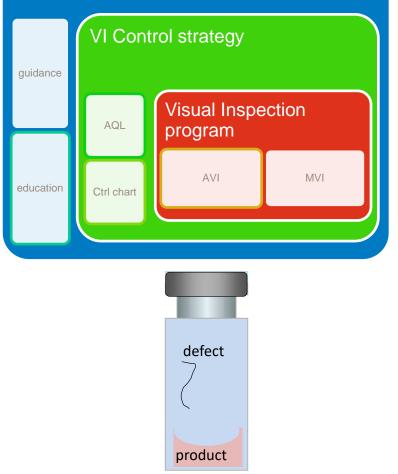


Visual inspection program in 3 layers:

- -The Core is AVI/MVI program, with strategy for DML / standard work / certification / validation
- The control strategy with ctrl chart and AQL guarantees that VI is kept under control
- -Continuous improvement is the goal of all VI activities with CAPA mngt. The Particle management is a key to success with particle control and associated WOW & education, product life cycle approach

Continuous improvement

& Particle management, product life cycle

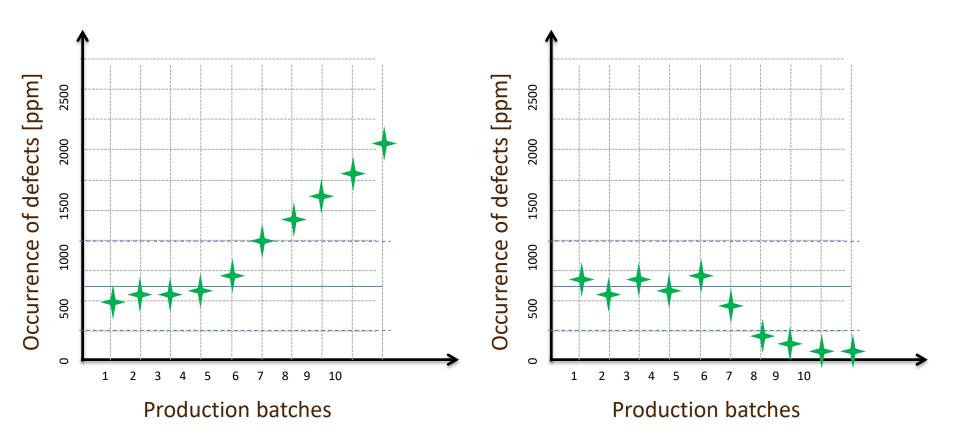




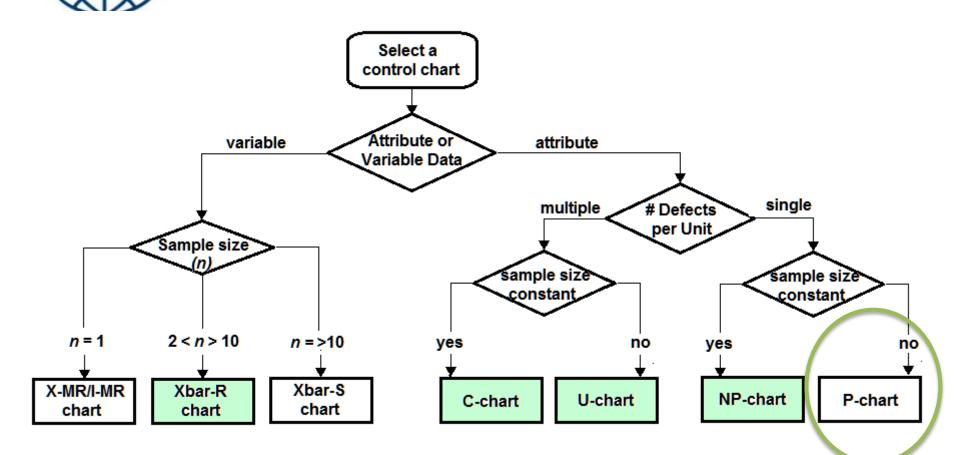
Data integrity





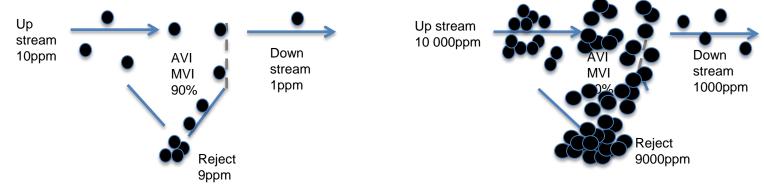












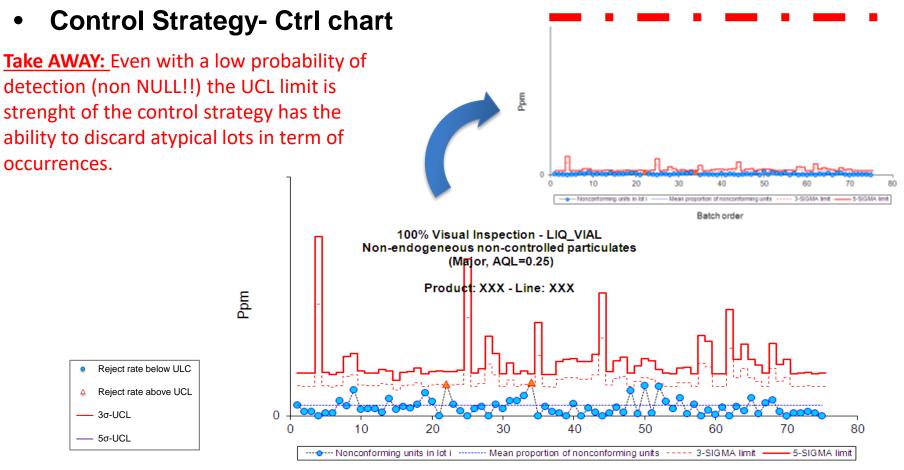
- Use of P' ctrl chart very powerfull to track any drift or atypical lot

$$UCL = \overline{p} + 3\sqrt{\frac{\overline{p}(1-\overline{p})}{n_i}} \qquad UCL = \overline{p} + 3\sqrt{\frac{p}{n_i}}$$

• 3 sigma probability follow binomial law

with 99,7% proportion of defective units





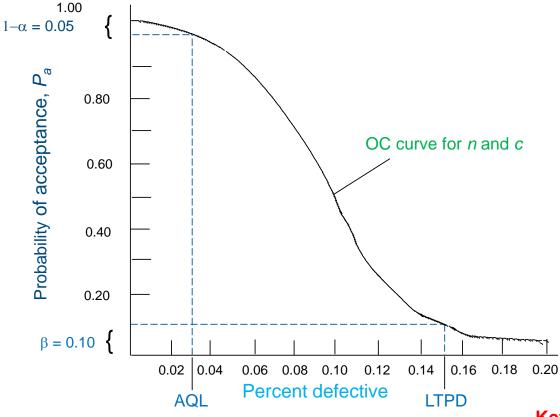
AQL Limit



Theory 5: Transition from Manual to automated visual Inspection Why is it important to maintain MVI ?

- AQL done in MVI
- AVI qualification is compared to MVI reference

7. Control strategy : AQL Sampling



- Acceptable quality level (AQL) Acceptable fraction defective in a lot
- Lot tolerance percent defective (LTPD or RQL)

Maximum fraction defective accepted in a lot

• **Producer's risk**, α

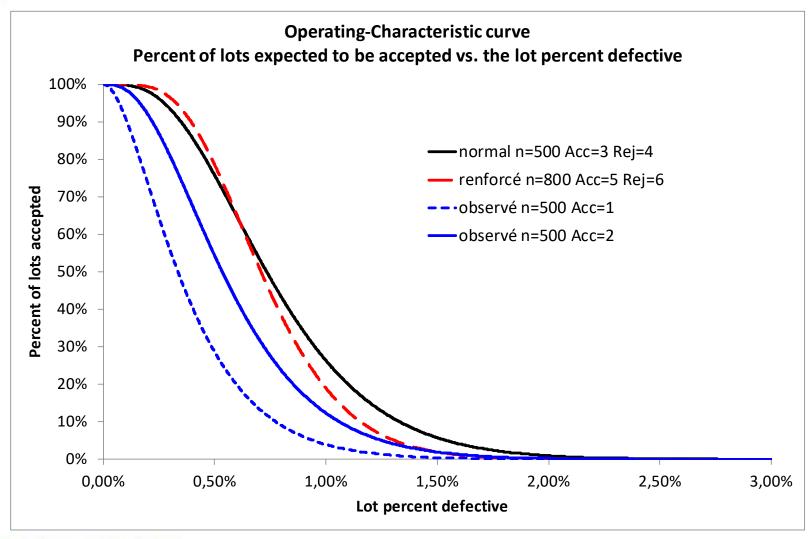
Type I error = P(reject a lot|probability (defective)=AQL)

Consumer's risk, β Type II error = P(accept a lot| probability(defective)=LTPD or RQL)

Key learning: AQL are always associated to RQL in an OC curve, this is the patient risk



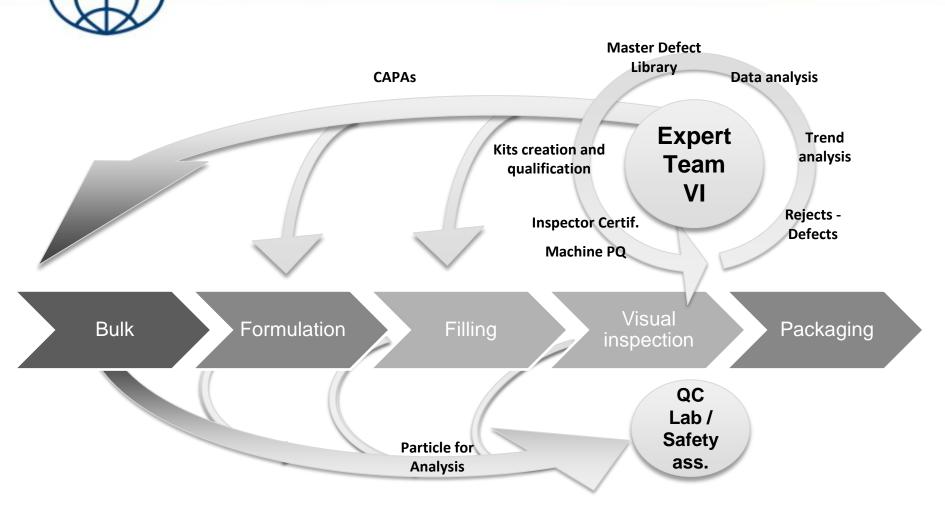


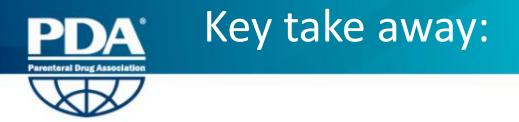




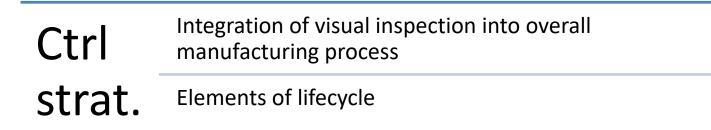
Visual Inspection of Freeze-Dried Products

Continuous Improvoment Loor





• In this section you have learnt:



Particle identification/ characterization

Defect libraries as dynamic database

AQL and control charting